

鋁氧化物對三(8-羥基喹啉)鋁有機雙穩態記憶體元件特性的影響

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摘要

在本篇論文當中，我們結合了 OLED 與有機雙穩態記憶體。主要的元件結構為在 ITO 玻璃基板跟鋁電極中，嵌入一層有機發光材料 Alq3，此元件具有發光和雙穩態的兩種特性；之後製作另一種結構的元件，在有機材料層中嵌入一層鋁金屬層。比較了兩種結構的電性之後，我們得到當有機材料層中嵌入一層鋁金屬層時，有機記憶體元件會有較佳的電性，例如：臨界電壓、ON/OFF 電流比、保留時間。但是卻遇到了問題：有機記憶體元件寫入訊號後卻無法抹除。我們推斷是因為 ITO 玻璃基板粗糙度影響了中間鋁金屬層的覆蓋性所造成。

因為 ITO 玻璃基板表面粗糙度會影響中間鋁金屬層的覆蓋性，在之後的篇章中，為了改善這個問題，我們用金取代 ITO 為下電極，並且增加中間金屬層的厚度。由於中間鋁金屬層的成分會影響有機雙穩態的特性，我們利用打氣電漿的方式讓中間金屬層形成鋁氧化物，成功的解決了有機雙穩態記憶體元件不易抹除的問題。之後，我們更改變了中間鋁金屬層的厚度跟打氣電漿的時間，並且討論對有機雙穩態特性的影響。

Study on the effect of Al-oxide complex on the performance of Alq₃-based organic bistable memory device

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Abstract

In this work, we fabricate an organic electrical bistable device (OBD) that combines with organic light emitting diodes. We report an organic bistable memory made of single organic layer embedded the ITO-structure and the Al electrode. And, we also fabricate the same device that interposes the inner metal film, Al. We compare with two kinds of OBDs. Then, the inner metal film that is interposed at organic layer improves the characteristic of electrical bistable effect, such as threshold voltage, on/off current ration, retention time. There is a problem that the OBDs doesn't erase information after processing. We think that roughness of ITO-substrate affects the coverage of inner metal film.

Later, we change the bottom ITO-glass electrode by Au and increase the thickness of inner metal film in order to improve the coverage of inner metal film. The method of inner metal film is treated with oxygen-plasma in order to form Al-O complex. And, there are several thickness of the inner metal layer is treated with oxygen-plasma for different time to discuss the characteristic of electrical bistable effect. Moreover, we are able to modify the electrical bistable properties by utilizing appropriate thickness of oxide layer and oxygen-plasma time.

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Content

Abstract (In Chinese).....	ii
Abstract (In English).....	iii
Acknowledgements.....	iv
Content.....	v
List of Tables.....	vii
List of Figures.....	viii

Chapter 1 Introduction 1

1.1 Introduction.....	1
1.1.1 Volatile Memory.....	1
1.1.2 Nonvolatile Memory.....	2
1.1.2.1 Flash Memory.....	2
1.1.2.2 Ferroelectric Random Access Memory.....	3
1.1.2.3 Magnetic Random Access Memory.....	4
1.1.2.4 OUM (Ovonic Unified Memory).	5
1.2 Organic Bistable Memory Device.	6
1.3 Motivation.....	8



Chapter 2 Organic Bistable Memory Devices 10

2.1 Introduction.....	10
2.2 Material.....	10
2.3 Thermal Instrument.....	11
2.4 Fabrication of the OBDs with ITO Substrate.	12
2.5 Electrical Characteristic Measurement.	14
2.6 Mechanism and Discussion.....	19
2.7 Conclusion.	27

Chapter 3 Al/Alq₃/Al/Alq₃/Au Bistable Memory Devices ... 28

3.1 Introduction.....	28
3.2 Fabrication of the OBDs with Au-electrode.	29
3.3 Electrical Characteristic Measurement.	30
3.4 Investigation of Thickness and Oxygen-plasma Time on the Inner Metal Film.....	33
3.5 The Re-writing Characteristic of the OBDs with Oxygen-plasma.	39
3.6 Conclusion.	41

Chapter 4 Conclusions and Future Work 42

4.1 Conclusions.....	42
4.2 Future Work.	43

References..... 45

Vita..... 48



List of Tables

Table 2-1	The parameter of fabrication process.....	14
Table 2-2	The information of the OBDs.....	24
Table 2-3	The compare of the two kinds of the OBDs.....	26
Table 3-1	The parameter of fabrication process.....	30
Table 3-2	The parameter of the Oxygen-plasma.....	33
Table 3-3	The relative parameters of the reported organic bistable device.....	41
Table 4-2	The device display optic bistable effect.....	44



List of Figures

Fig. 1-1 The structure of Flash memory.....	3
Fig. 1-2 The principle instruction of FeRAM.....	4
Fig. 1-3 (a). The structure of the MRAM. (b). The principle of the memory.....	5
Fig. 1-4 The basic structure of Phase-Change memory (OUM).....	6
Fig. 1-5 (a) the structure of the organic bistable device which was fabricated by the UCLA organic photoelectric research laboratory. (b)the chemical structure of AIDCN. (c) The basic structure and Current-Voltage characteristic of organic bistable Memory.....	7
Fig. 2-1 The chemical structure of Alq ₃	11
Fig. 2-2 The thermal deposition instrument,.....	12
Fig. 2-3 (a) The structure of the two kind of our device. (b) The top view of the device.....	13
Fig. 2-4 The HP-4156B.....	14
Fig. 2-5 <i>I-V</i> characteristics of ITO/Alq ₃ /Al. Current is expressed in absolute value. A abruptly jump in the low-current was observed on the way to the ON/OFF state transition around 1.8V . The bias is swept from 0 to 5 V, and sweep back 0 to 5 V.....	15
Fig. 2-6 The ON / OFF current ratio as a function of applied voltage.....	16
Fig. 2-7 <i>I-V</i> characteristics of ITO/Alq ₃ /Al/Alq ₃ /Al. A abruptly jump in the off-current was observed on the way to the off/on transition around 1.8V.....	17
Fig. 2-8 The ON / OFF current ratio as a function of applied voltage with inner	

metal film.....	18
Fig. 2-9 The Stability test on ITO/Alq ₃ /Al/ Alq ₃ /Al device in both ON and OFF states under applied voltage of +1V continuously. The retention time is over 1200sec.....	19
Fig. 2-10 Schematic illustrations of the possible bistable behavior mechanism (at the middle metal layer).....	20
Fig. 2-11 Schematic illustrations of the possible bistable behavior mechanism at the interface.....	21
Fig. 2-12 The device was indicated rewritability of the device.....	23
Fig. 2-13 I-V curve without the top Al electrode and mechanically contacted with a small Al tablet (the off-current is lower because the contact area in that case is smaller than with the evaporated Al contact). No switching has been observed for applied bias up to 5 V.....	25
Fig. 2-14 The AFM image of the roughness of ITO and Au.....	26
Fig. 3-1 The structure of the OBDs based on Au-electrode.....	30
Fig. 3-2 Typical current-voltage (<i>I</i> - <i>V</i>) characteristic of the OBDs.....	31
Fig. 3-3 The ON/OFF current ratio as a function of applied voltage.....	31
Fig. 3-4 The Stability test on Au/Alq ₃ /Al/Alq ₃ /LiF/Al device in both ON and OFF states under applied voltage of +1V continuously.....	32
Fig. 3-5 <i>I</i> - <i>V</i> curve of the oxygen-plasma time (30 s, 1 min and 4 min, respectively) with the same inner metal thickness, 20 nm.....	34
Fig. 3-6 (a) The retention time of the device treats plasma with 30s. (b) The retention time of the device treats plasma with 1min. (c) The ON/OFF ratio of the device treats plasma 30s. (d) The ON/OFF ratio of the device treats plasma 1min.....	34
Fig. 3-7 The absorb spectrum of the different oxygen-plasma time with an inner	

metal film is 20 nm.....	36
Fig. 3-8 I-V curve of the oxygen-plasma time (30 s, 1 min and 4 min, respectively) with the same inner metal thickness, 10 nm.....	37
Fig. 3-9 I-V curve of the oxygen-plasma time (30 s, 1 min and 4 min, respectively) with the same inner metal thickness, 50 nm.....	38
Fig. 3-10 The indicating re-writability of the device.....	39
Fig. 3-11 Write-read-erase cycles of the device. In the bottom curve indicate the device in the high and low conductance states.....	40
Fig. 4-1 The organic multi-state memory device.....	43

